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MEMS/NEMS Technology and Applications

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Editors

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Introduction

Collected over five volumes are the accepted papers from the International Conference on Optical Instruments and Technology 2008 (OIT'08). It is truly a great pleasure for me that the most recent progress in optical instrumentation technology is involved in the OIT'08 proceedings. I firmly believe that the papers included in these OIT'08 proceedings volumes will provide reference information in up-to-date techniques of optical instrumentation technology.

The International Conference on Optical Instruments and Technology 2008 (OIT'08) was sponsored by China Instrument and Control Society (CIS) and was cosponsored by SPIE. The academic and engineering activities of CIS included the fields of optical instruments, control and measurement, automatic sensor, device and instruments, MEMS/NEMS technology, auto-inspection engineering, and scientific instrumentation. CIS has experienced its developments for more than 20 years. Now CIS has more than 30 branches to cover the related instrument domain and the MICONEX international exhibition has its excellent reputation in high quality. SPIE has given great support to organize this international conference by collaborating with us in the whole organizing process from paper collection to the proceedings publication.

The OIT'08 conference collected over 500 papers from different countries or areas of the world. Over 900 authors came from more than 10 countries, including Canada, Japan, India, Romania, Russia, Singapore, Taiwan (China), USA, Pakistan, Spain and China. Published in these five volumes of the Proceedings of SPIE are close to 400 papers. The technical field of the presented papers at the conference covers a lot of current advanced technologies. The cutting-edge technologies and applications of optical instruments were discussed. Quite a few invited papers gave exciting achievements in the fields of optical instrument technology. It is evident that the OIT'08 conference has provided an excellent platform for participants and colleagues in research and development to share the technical progress and to develop new partnerships or broaden new markets.

Finally, on behalf of CIS and conference general chairs, I'd like to heartily thank our supporters and committee members for all they have done for this meeting. Thanks also go to all authors for their contributions; to all of the participants and friends for their interest, especially those who have traveled great distances and taken their time from their busy schedules to attend the meeting. I am also grateful to the staff of SPIE for their support and collaboration in publishing these volumes.

Zhuang Songlin
Chairman, China Instrument and Control Society

